

Amendments to the Specification:

Please replace paragraph [0005] with the following amended paragraph:

[0005] In order to solve the above-mentioned problem, an LED with a transparent conductive oxide layer formed on a p-type contact layer having high carrier
5 concentration has been disclosed in U.S. NO. 6,078,064. Because the transparent conductive oxide layer has high transmittance, the transparent conductive oxide layer can be thicker to better spread current in the transparent conductive oxide layer. Therefore, brightness of the LED can be increased by improving light-emitting characteristic of the LED. However, the carrier concentration of the p-type contact
10 layer needs to be greater than $5 \times 10^{18} \text{ cm}^{-3}$ to form a good ohmic contact upon the transparent conductive oxide layer. With regard to the ~~prior art~~ conventional semiconductor process, the p-type contact layer having high carrier concentration, however, is not easy to manufacture. It is well-known that the p-doped layer generally contains more defects, and the hydrogen atoms will affect formation of the p-doped
15 layer. The carriers with high concentration are not easy to obtain even if a large amount of p-type dopants are implanted. Though this art can effectively increase light intensity of the light emitted from the LED, contact resistance between the p-type contact layer and the transparent conductive oxide layer is so high that the forward bias voltage of the LED can adversely affect electric characteristics of the LED.

20 Please replace paragraph [0010] with the following amended paragraph:

[0010] It is an advantage of the present invention that a dual dopant contact layer is positioned between a transparent conductive oxide layer and the stacked semiconductor layers of the ~~claimed~~ novel LED. With the p-type impurity carriers and the n-type impurity carriers coexist in the dual dopant layer, the resistance associated
25 with the ohmic contact between the transparent conductive oxide layer and the stacked semiconductor layers of the LED is reduced. The dual dopant layer has a p-type impurity carriers and an n-type impurity carriers, as well as a corresponding p-type impurity energy level and a corresponding n-type impurity energy level coexist in the

energy bandgap of the dual dopant contact layer. When the LED is powered by a normal operating forward bias, the energy band of the dual dopant contact layer is strongly bended. The and conductive carriers are transmitted between the transparent conductive oxide layer and p-type contact cladding layer through the coexist p-type
5 and n-type impurity energy levels for forming a good ohmic contact when the elaimed novel LED is powered by a forward bias voltage. To sum up, the elaimed novel LED is capable of greatly increasing intensity of the emitted light without seriously making the forward bias voltage raised.

Please replace paragraph [0015] with the following amended paragraph:

10 [0015] The dual dopant contact layer 24 is doped by a p-type impurities impurity and an n-type impurities impurity simultaneously ~~to form both p-type carriers and n-type carriers within the dual dopant contact layer 24.~~ In the preferred embodiment, the concentration of the dopant impurities is equal to $1 \times 10^{19} \text{ cm}^{-3}$, and the thickness of the dual dopant contact layer 24 roughly equals 60 angstroms. As the experimental result
15 shown in the following Table 1, the preferred embodiment has a forward bias voltage greater than a forward bias voltage required by a prior-art conventional LED utilizing a Ni/Au metallic layer, and the forward bias voltage is raised from 3.15V to 3.16V. Please note that the forward bias voltage is measured when 20mA current passes through the elaimed novel LED 10 and the prior-art conventional LED. As shown in
20 Table 1, the preferred embodiment has light intensity greater than light intensity outputted by the prior-art conventional LED utilizing the Ni/Au metallic layer, and the light intensity is raised from 25.7mcd to 34.5mcd. That is, the light intensity is improved by 34.2%. In addition, the prior-art conventional LED with an n+ reverse tunneling contact layer is tested, and the result is shown in Table 1. It is obvious that
25 the prior-art conventional LED with the n+ reverse tunneling contact layer is capable of increasing the light intensity, but the required forward bias voltage is accordingly increased. Therefore, the LED 10 according to the present invention can improve the light intensity without greatly increasing the exerted forward bias voltage. Compared with the prior-art conventional LED, the LED 10 according to the present invention
30 apparently has better performance.

Please replace Table 1 with the following amended table:

Table 1

| | | | |
|----|------------------------------|------------|----------------|
| 5 | | Vf(V)@20mA | Intensity(mcd) |
| | Ni/Au metallic layer | 3.15 | 25.7 |
| | n+ reverse | 3.41 | 36.3 |
| 10 | tunneling contact layer | | |
| | claimed novel LED | 3.16 | 34.5 |

Please replace paragraph [0016] with the following amended paragraph:

[0016] Please note that the formation of the dual dopant contact layer 24 is not limited
 15 by the above-mentioned manufacturing method. Taking another LED emitting light
 with a wavelength equaling 526nm for example, this LED has the same structure
 shown in FIG. 1, but the dual dopant contact layer 24 for this LED is manufactured by
 another process. After the p-type contact layer 22 is fabricated, an n-type InGaN
 contact layer with a thickness equaling 20 angstroms is then stacked on the p-type
 20 contact layer 22. After the n-type InGaN contact layer successfully grows on the
 p-type contact layer 22, an annealing process with a cooling rate less than 40°C/min is
 applied to make the n-type dopant impurity within the n-type InGaN contact layer and
 the p-type ~~dopants~~ impurity within the p-type contact layer 22 diffuse to each other.
 Then, the original n-type InGaN contact layer contains both the n-type dopants
 25 impurity and the p-type dopants impurity, and the InGaN contact layer becomes a dual
 dopant contact layer. The dual dopant contact layer then has the concentration of
 n-type impurity carriers equaling $8 \times 10^{18} \text{ cm}^{-3}$, and has the concentration of p-type
impurity carriers equaling $5 \times 10^{18} \text{ cm}^{-3}$. The experimental result associated with the
 above LED is shown in Table 2.

30 Please replace Table 2 with the following amended table:

Table 2

| | Vf(V)@20mA | Intensity(mcd) |
|---------------------------------|------------|----------------|
| 5 Ni/Au metallic layer | 3.11 | 137.6 |
| N+ reverse | 3.56 | 171.6 |
| tunneling contact layer | | |
| 10 elaimed novel LED | 3.20 | 178.4 |

Please replace paragraph [0017] with the following amended paragraph:

[0017] Compared to the ~~prior-art~~ conventional LED with the Ni/Au metallic layer, the ~~elaimed novel~~ LED raises the light intensity from 137.6mcd to 178.4mcd. That is, the light intensity is then improved by 29.8%. Similarly, the ~~prior-art~~ conventional LED with the n+ reverse tunneling contact layer is tested, and the result is also shown in Table 2. It is obvious that the ~~prior-art~~ conventional LED with the n+ reverse tunneling contact layer is capable of increasing the light intensity, but the required forward bias voltage is accordingly increased to be 3.56V that is greatly higher than the forward bias voltage (3.11V) required by the ~~prior-art~~ conventional LED with the Ni/Au metallic layer. However, the forward bias voltage measured for the ~~elaimed novel~~ LED is merely raised from 3.11V to 3.20V. Therefore, the LED of to the present invention can improve the light intensity without greatly increasing the exerted forward bias voltage. Compared with the ~~prior-art~~ conventional LED, the LED of to the present invention apparently performs better.

Please replace paragraph [0019] with the following amended paragraph:

[0019] The n-type conductive substrate 42 is made of one material selected from a material group consisting of GaN, SiC, Si, AlN, ZnO, MgO, GaP, GaAs, and Ge. The

above-mentioned insulating substrate 12 is made of one semiconductor material selected from a material group consisting of sapphire, LiGaO_2 , and LiAlO_2 . The above-mentioned buffer layer 14 is made of AlInGaN-based material or II-nitride-based material. The above-mentioned p-type contact layer 16 comprises
 5 $\text{Al}_{x1}\text{In}_{y1}\text{Ga}_{1-(x1+y1)}\text{N}$ ($0 \leq x1 \leq 1$; $0 \leq y1 \leq 1$; and $0 \leq x1+y1 \leq 1$). The above-mentioned n-type cladding layer 17 comprises $\text{Al}_x\text{Ga}_{1-x}\text{N}$, and $0 \leq x \leq 1$. The above-mentioned multiple quantum well light emitting layer 18 comprises r InGaN quantum wells and (r+1) InGaN barriers so that both sides of each InGaN quantum well is sandwiched in between two InGaN barriers. Please note that r is not less than 1, each InGaN quantum
 10 well is formed by $\text{In}_f\text{Ga}_{1-f}\text{N}$, and each InGaN barrier is formed by $\text{In}_f\text{Ga}_{1-f}\text{N}$ ($0 \leq f < e \leq 1$). The above-mentioned p-type cladding layer 20 comprises ~~$\text{Al}_x\text{Ga}_{1-x}\text{N}$, wherein $0 \leq x \leq 1$~~ $\text{Al}_y\text{Ga}_{1-y}\text{N}$, wherein $0 \leq y \leq 1$. The above-mentioned p-type contact layer 22 being made of $\text{Al}_{x2}\text{In}_{y2}\text{Ga}_{1-(x2+y2)}\text{N}$ ($0 \leq x2 \leq 1$; $0 \leq y2 \leq 1$; and $0 \leq x2+y2 \leq 1$). The above-mentioned transparent conductive oxide layer 26 is made of one semiconductor
 15 material selected from a material group consisting of Indium-tin oxide (ITO), Cadmium-tin oxide, Antimony-tin oxide (ATO), Zinc oxide (ZnO), and Zinc-tin oxide. The above-mentioned dual dopant contact layer 24 is made of GaN-based material. The above-mentioned n-type dopant is made of one material selected from a material group consisting of Si, Ge, Sn, Te, O, S, and C, and the p-type ~~dopant~~ dopant is made
 20 of one material selected from a material group consisting of Mg, Zn, Be, and Ca.

Please replace paragraph [0020] with the following amended paragraph:

[0020] In contrast to the ~~prior art~~ conventional LED, the ~~claimed novel~~ LED positions a dual dopant layer between a transparent conductive oxide layer and the light emitting stacked structure. With the p-type ~~carriers~~ impurity and the n-type ~~carriers~~
 25 impurity coexistent in the dual dopant layer, the resistance associated with the ohmic contact between the transparent conductive oxide layer and the light emitting stacked structure is reduced. Therefore, the ~~claimed novel~~ LED is capable of solving the problem in the ~~prior art~~ conventional LED. Because the dual dopant layer has p-type ~~carriers~~ impurity and n-type impurity carriers, an energy level associated with the

n-type ~~carriers~~ impurity and an energy level associated with the p-type ~~carriers~~ impurity ~~coexist~~ ~~are located~~ within the energy band gap of the dual dopant layer. Therefore, when the ~~elaimed~~ novel LED is powered by a forward bias voltage, carriers are conductive through both coexisted impurity energy levels. ~~Hence~~ Therefore,

5 conductive carriers are transmitted between the transparent conductive oxide layer and p-type cladding layer for forming a good ohmic contact between the transparent conductive oxide layer and the stacked semiconductor layers of the LED. With this transmission mechanism, it is unnecessary to fabricate a ~~prior-art~~ conventional LED of a highly-doped p-type contact layer with a p-type carrier concentration, as well as a

10 high conductivity. Therefore, the problem related to forming the ~~prior-art~~ the high highly carrier concentration doped p-type contact layer of the conventional LED is solved by the ~~elaimed~~ novel LED. In addition, the ~~elaimed~~ novel LED is capable of greatly increasing intensity of the emitted light without seriously raising forward bias voltage. To sum up, the overall performance of the ~~elaimed~~ novel LED is better than

15 the performance of the conventional ~~prior-art~~ LED.